



Attorney Docket No. 108298722US  
Disclosure No. 02-1565.00/US

PTO/SB/08a/b (08-03)  
Approved for use through 07/31/2008. OMB 0651-0031  
U.S. Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE

Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

Substitute for form 1449A/B/PTO  <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  (Use as many sheets as necessary)		<b>Complete If Known</b>	
		Application Number	10/665,908-Conf. #7052
		Filing Date	September 18, 2003
		First Named Inventor	Demetrius Sarigiannis
		Art Unit	1763
		Examiner Name	Rudy Zervigon
Sheet	1	of	13
		Attorney Docket Number	108298722US

U.S. PATENT DOCUMENTS					
Examiner Initials*	Cite No. <sup>1</sup>	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code <sup>2</sup> (if known)			
KMS		US-10/767,298	Filed 01-28-2004	Zheng et al.	
KMS		US-11/027,825	Filed 12-29-2004	Derderian et al.	
KMS		US-10/933,604	Filed 09-02-2004	Carpenter et al.	
KMS		US-10/687,458	Filed 10-15-2003	Kubista et al.	
KMS		US-10/683,424	Filed 10-10-2003	Mardian	
KMS		US-10/839,316	Filed 05-05-2004	Saragiannis et al.	
KMS		US-10/814,573	Filed 03-31-2004	Gealy et al.	
KMS		US-11/043,629	Filed 01-25-2005	Rueger et al.	
KMS		US-11/018,142	Filed 12-20-2004	Rueger et al.	
KMS		US-10/840,571	Filed 05-06-2004	Dando et al.	
KMS		US-10/859,883	Filed 06-02-2004	Miller et al.	
KMS		US-10/683,606	Filed 10-09-2003	Derderian	
KMS		US-11/027,809	Filed 12-29-2004	Carpenter et al.	
KMS		US-579,269	03-23-1897	Hent	
KMS		US-3,618,919	11-09-1971	Beck	
KMS		US-3,620,934	11-16-1971	Endle	
KMS		US-3,630,881	12-28-1971	Lester et al.	
KMS		US-3,630,769	12-28-1971	Hart et al.	
KMS		US-3,634,212	01-11-1972	Valayll et al.	
KMS		US-4,018,949	04-19-1977	Donokowski et al.	
KMS		US-4,242,182	12-30-1980	Popescu	

Substitute for form 1449A/B/PTO  <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  (Use as many sheets as necessary)				<b>Complete if Known</b>	
				Application Number	10/665,908—Conf. #7052
				Filing Date	September 18, 2003
				First Named Inventor	Demetrius Sarigiannis
				Art Unit	1763
				Examiner Name	Rudy Zervigon
Sheet	2	of	13	Attorney Docket Number	108298722US

KMS	US-4,269,625	05-26-1981	Molenaar	
KMS	US-4,289,061	09-15-1981	Emmett	
KMS	US-4,397,753	08-09-1983	Czaja	
KMS	US-4,438,724	03-27-1984	Doehler et al.	
KMS	US-4,469,801	09-04-1984	Hirai et al.	
KMS	US-4,545,136	10-08-1985	Izu et al.	
KMS	US-4,590,042	05-20-1986	Drage	
KMS	US-4,681,777	07-21-1987	Engelken et al.	
KMS	US-4,826,579	05-02-1989	Westfall	
KMS	US-4,948,979	08-14-1990	Munakata et al.	
KMS	US-4,949,669	08-21-1990	Ishii et al.	
KMS	US-4,966,646	10-30-1990	Zdeblick	
KMS	US-4,977,106	12-11-1990	Smith	
KMS	US-5,076,205	12-31-1991	Vowles et al.	
KMS	US-5,091,207	02-25-1992	Tanaka	
KMS	US-5,131,752	07-21-1992	Yu et al.	
KMS	US-5,136,975	08-11-1992	Bartholomew et al.	
KMS	US-5,172,849	12-22-1992	Barten et al.	
KMS	US-5,200,023	04-06-1993	Gifford et al.	
KMS	US-5,223,113	06-29-1993	Kaneko et al.	
KMS	US-5,232,749	08-03-1993	Gilton	
KMS	US-5,248,527	09-28-1993	Uchida et al.	
KMS	US-5,364,219	11-15-1994	Takahashi et al.	
KMS	US-5,377,429	01-03-1995	Sandhu et al.	
KMS	US-5,380,396	01-10-1995	Shikida et al.	
KMS	US-5,409,129	04-25-1995	Tsukada et al.	
KMS	US-5,418,180	05-23-1995	Brown	
KMS	US-5,427,666	06-27-1995	Mueller et al.	
KMS	US-5,433,835	07-18-1995	Demaray et al.	
KMS	US-5,445,491	08-29-1995	Nakagawa et al.	
KMS	US-5,480,818	01-02-1996	Matsumoto et al.	
KMS	US-5,498,292	03-12-1996	Ozaki	

Examiner Signature	/Kelly Stouffer/	Date Considered	08/21/2006
-----------------------	------------------	--------------------	------------

Substitute for form 1449A/B/PTO  <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  (Use as many sheets as necessary)				<b>Complete If Known</b>	
				Application Number	10/665,908—Conf. #7052
				Filing Date	September 18, 2003
				First Named Inventor	Demetrius Sarigiannis
				Art Unit	1763
				Examiner Name	Rudy Zervigon
Sheet	3	of	13	Attorney Docket Number	108298722US

KMS	US-5,500,256	03-19-1996	Watabe	
KMS	US-5,522,934	06-04-1996	Suzuki et al.	
KMS	US-5,536,317	07-16-1996	Crain et al.	
KMS	US-5,562,800	10-08-1996	Kawamura	
KMS	US-5,589,002	12-31-1996	Su	
KMS	US-5,592,581	01-07-1997	Okase	
KMS	US-5,595,606	01-21-1997	Fujikawa et al.	
KMS	US-5,599,513	02-04-1997	Masaki et al.	
KMS	US-5,624,498	04-29-1997	Lee et al.	
KMS	US-5,626,936	05-06-1997	Alderman	
KMS	US-5,640,751	06-24-1997	Faria	
KMS	US-5,643,394	07-01-1997	Maydan et al.	
KMS	US-5,654,589	08-05-1997	Huang et al.	
KMS	US-5,693,288	12-02-1997	Nakamura	
KMS	US-5,729,896	03-24-1998	Dalal et al.	
KMS	US-5,746,434	05-05-1998	Boyd et al.	
KMS	US-5,766,364	06-16-1998	Ishida et al.	
KMS	US-5,769,952	06-23-1998	Komino	
KMS	US-5,788,778	08-04-1998	Shang et al.	
KMS	US-5,792,700	08-11-1998	Turner et al.	
KMS	US-5,792,269	08-11-1998	Deacon et al.	
KMS	US-5,820,641	10-13-1998	Gu et al.	
KMS	US-5,827,370	10-27-1998	Gu	
KMS	US-5,833,888	11-10-1998	Arya et al.	
KMS	US-5,846,330	12-08-1998	Quirk et al.	
KMS	US-5,846,275	12-08-1998	Lane et al.	
KMS	US-5,851,849	12-22-1998	Comizzoli et al.	
KMS	US-5,865,417	02-02-1999	Harris et al.	
KMS	US-5,879,459	03-09-1999	Gadgil et al.	
KMS	US-5,895,530	04-20-1999	Shrotriya et al.	
KMS	US-5,908,947	06-01-1999	Vaartstra	
KMS	US-5,932,286	08-03-1999	Beinglass et al.	

Examiner Signature	/Kelly Stouffer/	Date Considered	08/21/2006
-----------------------	------------------	--------------------	------------

Substitute for form 1449A/B/PTO  <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  <i>(Use as many sheets as necessary)</i>				<b>Complete if Known</b>	
				Application Number	10/665,908—Conf. #7052
				Filing Date	September 18, 2003
				First Named Inventor	Demetrius Sarigiannis
				Art Unit	1763
				Examiner Name	Rudy Zervigon
Sheet	4	of	13	Attorney Docket Number	108298722US

KMS		US-5,953,634	09-14-1999	Kajita et al.	
KMS		US-5,956,613	09-21-1999	Zhao et al.	
KMS		US-5,968,587	10-19-1999	Frankel	
KMS		US-5,972,430	10-26-1999	DiMeo, Jr. et al.	
KMS		US-5,994,181	11-30-1999	Hsieh et al.	
KMS		US-5,997,588	12-07-1999	Goodwin et al.	
KMS		US-6,008,086	12-28-1999	Schuegraf et al.	
KMS		US-6,032,923	03-07-2000	Biegelsen et al.	
KMS		US-6,042,652	03-28-2000	Hyun et al.	
KMS		US-6,045,620	04-04-2000	Tepman et al.	
KMS		US-6,059,885	05-09-2000	Ohashi et al.	
KMS		US-6,062,256	05-16-2000	Miller et al.	
KMS		US-6,070,551	06-06-2000	Li et al.	
KMS		US-6,080,446	06-27-2000	Tobe et al.	
KMS		US-6,079,426	06-27-2000	Subrahmanyam et al.	
KMS		US-6,086,677	07-11-2000	Umotoy et al.	
KMS		US-6,089,543	07-18-2000	Freerks	
KMS		US-6,109,206	08-29-2000	Maydan et al.	
KMS		US-09/651,037	08-30-2000	Mardian	
KMS		US-6,123,107	09-26-2000	Selser et al.	
KMS		US-6,129,331	10-10-2000	Henning et al.	
KMS		US-6,139,700	10-31-2000	Kang et al.	
KMS		US-6,143,659	11-07-2000	Leem	
KMS		US-6,143,077	11-07-2000	Ikeda et al.	
KMS		US-6,143,078	11-07-2000	Ishikawa et al.	
KMS		US-6,144,060	11-07-2000	Park et al.	
KMS		US-6,149,123	11-21-2000	Harris et al.	
KMS		US-6,160,243	12-12-2000	Cozad	
KMS		US-6,161,500	12-19-2000	Kopacz et al.	
KMS		US-6,174,366	01-16-2001	Ihantola	
KMS		US-6,174,377	01-16-2001	Doering et al.	
KMS		US-6,174,809	01-16-2001	Kang et al.	

Examiner Signature	/Kelly Stouffer/	Date Considered	08/21/2006
--------------------	------------------	-----------------	------------

Substitute for form 1449A/B/PTO  <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  (Use as many sheets as necessary)				<b>Complete if Known</b>	
				Application Number	10/665,908—Conf. #7052
				Filing Date	September 18, 2003
				First Named Inventor	Demetrius Sarigiannis
				Art Unit	1763
				Examiner Name	Rudy Zervigon
Sheet	5	of	13	Attorney Docket Number	108298722US

KMS	US-6,173,673	01-16-2001	Golovato et al.	
KMS	US-6,178,660	01-30-2001	Emmi et al.	
KMS	US-6,182,603	02-02-2001	Shang et al.	
KMS	US-6,192,827	02-27-2001	Welch et al.	
KMS	US-6,194,628	02-27-2001	Pang et al.	
KMS	US-6,193,802	02-27-2001	Pang et al.	
KMS	US-6,197,119	03-06-2001	Dozoretz et al.	
KMS	US-6,200,415	03-13-2001	Maraschin	
KMS	US-6,203,613	03-20-2001	Gates et al.	
KMS	US-6,206,972	03-27-2001	Dunham	
KMS	US-6,211,078	04-03-2001	Matthews	
KMS	US-6,211,033	04-03-2001	Sandhu et al.	
KMS	US-6,210,754	04-03-2001	Lu et al.	
KMS	US-6,214,714	04-10-2001	Wang et al.	
KMS	US-6,237,394	05-29-2001	Harris et al.	
KMS	US-6,237,529	05-29-2001	Spahn	
KMS	US-6,245,192	06-12-2001	Dhindsa et al.	
KMS	US-6,255,222	07-03-2001	Xia et al.	
KMS	US-6,263,829	07-24-2001	Schneider et al.	
KMS	US-2001/0010309-A1	08-02-2001	Van Bilsen	
KMS	US-6,270,572	08-07-2001	Kim et al.	
KMS	US-2001/0011526-A1	08-09-2001	Doering et al.	
KMS	US-6,280,584	08-28-2001	Kumar et al.	
KMS	US-6,287,980	09-11-2001	Hanazaki et al.	
KMS	US-6,287,965	09-11-2001	Kang et al.	
KMS	US-6,291,337	09-18-2001	Sidhwa	
KMS	US-6,290,491	09-18-2001	Shahvandi et al.	
KMS	US-2001/0024387-A1	09-27-2001	Raaljmakers et al.	
KMS	US-6,297,539	10-02-2001	Ma et al.	
KMS	US-6,302,964	10-16-2001	Umotoy et al.	
KMS	US-6,302,965	10-16-2001	Umotoy et al.	
KMS	US-6,303,953	10-16-2001	Doan et al.	

Examiner Signature	/Kelly Stouffer/	Date Considered	08/21/2006
-----------------------	------------------	--------------------	------------

Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

Substitute for form 1449A/B/PTO  <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  <i>(Use as many sheets as necessary)</i>				<b>Complete If Known</b>	
				Application Number	10/665,908—Conf. #7052
				Filing Date	September 18, 2003
				First Named Inventor	Demetrius Sarigiannis
				Art Unit	1763
				Examiner Name	Rudy Zervigon
Sheet	6	of	13	Attorney Docket Number	108298722US

KMS		US-2001/0029892-A1	10-18-2001	Cook et al.	
KMS		US-6,305,314	10-23-2001	Sneh et al.	
KMS		US-6,309,161	10-30-2001	Hofmeister	
KMS		US-6,315,859	11-13-2001	Donohoe	
KMS		US-2001/0045187-A1	11-29-2001	Uhlenbrock	
KMS		US-6,329,297	12-11-2001	Ballish et al.	
KMS		US-2001/0054484-A1	12-27-2001	Komino	
KMS		US-2002/0007790-A1	01-24-2002	Park	
KMS		US-6,342,277	01-29-2002	Sherman	
KMS		US-6,346,477	02-12-2002	Kaloyeros et al.	
KMS		US-6,347,602	02-19-2002	Goto et al.	
KMS		US-6,347,918	02-19-2002	Blahnik	
KMS		US-2002/0020353-A1	02-21-2002	Redemann et al.	
KMS		US-6,355,561	03-12-2002	Sandhu et al.	
KMS		US-6,358,323	03-19-2002	Schmitt et al.	
KMS		US-2002/0043216-A1	04-18-2002	Hwang et al.	
KMS		US-6,374,831	04-23-2002	Chandran et al.	
KMS		US-2002/0052097-A1	05-02-2002	Park	
KMS		US-6,387,185	05-14-2002	Doering et al.	
KMS		US-6,387,207	05-14-2002	Janakiraman et al.	
KMS		US-2002/0076508-A1	06-20-2002	Chiang et al.	
KMS		US-2002/0076490-A1	06-20-2002	Chiang et al.	
KMS		US-2002/0073924-A1	06-20-2002	Chiang et al.	
KMS		US-2002/0076507-A1	06-20-2002	Chiang et al.	
KMS		US-6,420,230	07-16-2002	Derderian et al.	
KMS		US-6,419,462	07-16-2002	Horie et al.	
KMS		US-6,420,742	07-16-2002	Ahn et al.	
KMS		US-2002/0094689-A1	07-18-2002	Park	
KMS		US-2002/0100418-A1	08-01-2002	Sandhu et al.	
KMS		US-6,428,859	08-06-2002	Chiang et al.	
KMS		US-2002/0104481-A1	08-08-2002	Chiang et al.	
KMS		US-6,432,831	08-13-2002	Dhindsa et al.	

Examiner Signature	/Kelly Stouffer/	Date Considered	08/21/2006
--------------------	------------------	-----------------	------------

Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

Substitute for form 1449A/B/PTO  <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  (Use as many sheets as necessary)				<b>Complete if Known</b>	
				Application Number	10/665,908—Conf. #7052
				Filing Date	September 18, 2003
				First Named Inventor	Demetrius Sarigiannis
				Art Unit	1763
				Examiner Name	Rudy Zervigon
Sheet	7	of	13	Attorney Docket Number	108298722US

KMS		US-6,432,259	08-13-2002	Noorbaksh et al.	
KMS		US-6,432,256	08-13-2002	Raoux	
KMS		US-2002/0110991-A1	08-15-2002	Li	
KMS		US-2002/0108714-A1	08-15-2002	Doering et al.	
KMS		US-6,435,865	08-20-2002	Tseng et al.	
KMS		US-6,444,039	09-03-2002	Nguyen	
KMS		US-2002/0127745-A1	09-12-2002	Lu et al.	
KMS		US-6,450,117	09-17-2002	Murugesh et al.	
KMS		US-6,451,119	09-17-2002	Sneh et al.	
KMS		US-2002/0129768-A1	09-19-2002	Carpennter et al.	
KMS		US-6,458,416	10-01-2002	Derderian et al.	
KMS		US-6,461,931	10-08-2002	Eldridge	
KMS		US-6,461,436	10-08-2002	Campbell et al.	
KMS		US-2002/0144655-A1	10-10-2002	Chiang et al.	
KMS		US-2002/0146512-A1	10-10-2002	Rossmann	
KMS		US-2002/0164420-A1	11-07-2002	Derderian et al.	
KMS		US-2002/0162506-A1	11-07-2002	Sneh et al.	
KMS		US-2002/0185067-A1	12-12-2002	Upham	
KMS		US-2002/0195201-A1	12-26-2002	Beer	
KMS		US-2002/0197402-A1	12-26-2002	Chiang et al.	
KMS		US-2002/0195056-A1	12-26-2002	Sandhu et al.	
KMS		US-2003/0003730-A1	01-02-2003	Li	
KMS		US-2003/0000473-A1	01-02-2003	Chae et al.	
KMS		US-2003/0003697-A1	01-02-2003	Agarwal et al.	
KMS		US-6,503,330	01-07-2003	Sneh et al.	
KMS		US-6,506,254	01-14-2003	Bosch et al.	
KMS		US-2003/0013320-A1	01-16-2003	Kim et al.	
KMS		US-6,509,280	01-21-2003	Choi	
KMS		US-2003/0023338-A1	01-30-2003	Chin et al.	
KMS		US-2003/0024477-A1	02-06-2003	Okuda et al.	
KMS		US-2003/0027428-A1	02-06-2003	Ng et al.	
KMS		US-2003/0027431-A1	02-06-2003	Sneh et al.	

Examiner Signature	/Kelly Stouffer/	Date Considered	08/21/2006
--------------------	------------------	-----------------	------------

Substitute for form 1449A/B/PTO  <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  <i>(Use as many sheets as necessary)</i>				<b>Complete if Known</b>	
				Application Number	10/665,908-Conf. #7052
				Filing Date	September 18, 2003
				First Named Inventor	Demetrius Sarigiannis
				Art Unit	1763
				Examiner Name	Rudy Zervigon
Sheet	8	of	13	Attorney Docket Number	108298722US

KMS	US-10/365,085	02-11-2003	Carpenter et al.	
KMS	US-2003/0037729-A1	02-27-2003	DeDontney et al.	
KMS	US-6,534,395	03-18-2003	Werkhoven et al.	
KMS	US-6,534,007	03-18-2003	Blonigan et al.	
KMS	US-2003/0060030-A1	03-27-2003	Lee et al.	
KMS	US-6,540,838	04-01-2003	Sneh et al.	
KMS	US-6,541,353	04-01-2003	Sandhu et al.	
KMS	US-2003/0066483-A1	04-10-2003	Lee et al.	
KMS	US-2003/0070618-A1	04-17-2003	Campbell et al.	
KMS	US-2003/0070617-A1	04-17-2003	Kim et al.	
KMS	US-2003/0070609-A1	04-17-2003	Campbell et al.	
KMS	US-6,551,929	04-22-2003	Kori et al.	
KMS	US-2003/0075273-A1	04-24-2003	Kilpela et al.	
KMS	US-2003/0079686-A1	05-01-2003	Chen et al.	
KMS	US-6,562,140	05-13-2003	Bondestam et al.	
KMS	US-6,562,141	05-13-2003	Clarke	
KMS	US-2003/0098372-A1	05-29-2003	Kim	
KMS	US-2003/0098419-A1	05-29-2003	Ji et al.	
KMS	US-6,573,184	06-03-2003	Park	
KMS	US-2003/0106490-A1	06-12-2003	Jallepally et al.	
KMS	US-6,579,372	06-17-2003	Park	
KMS	US-6,579,374	06-17-2003	Bondestam et al.	
KMS	US-2003/0121608-A1	07-03-2003	Chen et al.	
KMS	US-6,596,085	07-22-2003	Schmitt et al.	
KMS	US-6,602,346	08-05-2003	Gochberg	
KMS	US-2003/0159780-A1	08-28-2003	Carpenter et al.	
KMS	US-6,630,201	10-07-2003	Chiang et al.	
KMS	US-2003/0194862-A1	10-16-2003	Mardian et al.	
KMS	US-2003/0192645-A1	10-16-2003	Liu	
KMS	US-6,635,965	10-21-2003	Lee et al.	
KMS	US-6,638,879	10-28-2003	Hsieh et al.	
KMS	US-6,638,672	10-28-2003	Deguchi	

Examiner Signature	/Kelly Stouffer/	Date Considered	08/21/2006
--------------------	------------------	-----------------	------------



Substitute for form 1449A/B/PTO				<b>Complete if Known</b>	
<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  <i>(Use as many sheets as necessary)</i>				Application Number	10/665,908—Conf. #7052
				Filing Date	September 18, 2003
				First Named Inventor	Demetrius Sarigiannis
				Art Unit	1763
				Examiner Name	Rudy Zervigon
Sheet	9	of	13	Attorney Docket Number	108298722US

KMS	US-2003/0203109-A1	10-30-2003	Dando et al.	
KMS	US-2003/0200926-A1	10-30-2003	Dando et al.	
KMS	US-6,641,673	11-04-2003	Yang	
KMS	10/733,523	12-10-2003	Beaman et al.	
KMS	US-6,673,196	01-06-2004	Oyabu	
KMS	US-2004/0003777-A1	01-08-2004	Carpenter et al.	
KMS	US-2004/0007188-A1	01-15-2004	Burkhart et al.	
KMS	US-2004/0035358-A1	02-26-2004	Basceri et al.	
KMS	US-2004/0040502-A1	03-04-2004	Basceri et al.	
KMS	US-2004/0040503-A1	03-04-2004	Basceri et al.	
KMS	US-6,704,913	03-09-2004	Rossman	
KMS	US-6,706,334	03-16-2004	Kobayashi et al.	
KMS	US-6,705,345	03-16-2004	Bifano	
KMS	US-2004/0083959-A1	05-06-2004	Carpenter et al.	
KMS	US-2004/0083961-A1	05-06-2004	Basceri	
KMS	US-2004/0083960-A1	05-06-2004	Dando	
KMS	US-2004/0099377-A1	05-27-2004	Newton et al.	
KMS	US-2004/0124131-A1	07-01-2004	Aitchison et al.	
KMS	US-2004/0154538-A1	08-12-2004	Carpenter et al.	
KMS	US-6,818,249-B2	11-16-2004	Derderian	
KMS	US-2004/0226507-A1	11-18-2004	Carpenter et al.	
KMS	US-6,821,347-B2	11-23-2004	Carpenter et al.	
KMS	US-6,838,114-B2	01-04-2005	Carpenter et al.	
KMS	US-2005/0016984-A1	01-27-2005	Dando	
KMS	US-2005/0022739-A1	02-03-2005	Carpenter et al.	
KMS	US-2005/0028734-A1	02-10-2005	Carpenter et al.	
KMS	US-2005/0039680-A1	02-24-2005	Beaman et al.	
KMS	US-2005/0039686-A1	02-24-2005	Zheng et al.	
KMS	US-6,861,094-B2	03-01-2005	Derderian et al.	
KMS	US-2005/0045100-A1	03-03-2005	Derderian	
KMS	US-2005/0045102-A1	03-03-2005	Zheng et al.	
KMS	US-2005/0059261-A1	03-17-2005	Basceri et al.	

Examiner Signature	/Kelly Stouffer/	Date Considered	08/21/2006
--------------------	------------------	-----------------	------------

Substitute for form 1449A/B/PTO				<b>Complete If Known</b>	
<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  <i>(Use as many sheets as necessary)</i>				Application Number	10/665,908-Conf. #7052
				Filing Date	September 18, 2003
				First Named Inventor	Demetrius Sarigiannis
				Art Unit	1763
				Examiner Name	Rudy Zervigon
Sheet	10	of	13	Attorney Docket Number	108298722US

FOREIGN PATENT DOCUMENTS						
Examiner Initials*	Cite No.	Foreign Patent Document Country Code <sup>3</sup> -Number <sup>4</sup> -Kind Code <sup>5</sup> (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T <sup>6</sup>
KMS		JP-4-213818-A	08-04-1992	Sony Corp		
KMS		JP-2001-82682-A	03-30-2001	Matsushita Refrig Co Ltd.		√
KMS		JP-1-273991-A	11-01-1989	Ishikawajima Harima Heavy Ind. Co. Ltd.		
KMS		JP-63-256460-A	10-24-1988	Oki Electric Ind. Co. Ltd.		
KMS		WO-00/79019-A1	12-28-2000	Gadgil		
KMS		WO-03/016587-A1	02-27-2003	ASM Microchemistry OY, et al.		
KMS		WO-00/65649-A1	11-02-2000	Tokyo Electron Limited		
KMS		WO-03/008662-A2	01-30-2003	Applied Materials, Inc.		
KMS		WO-03/028069-A2	04-03-2003	Applied Materials, Inc.		
KMS		WO-02/095807-A2	11-28-2002	Integrated Materials, Inc.		
KMS		WO-02/073660-A2	09-19-2002	ASML US, Inc.		
KMS		WO-00/63952-A1	10-26-2000	Integrated Materials, Inc.		
KMS		WO-03/033762-A1	04-24-2003	Micron Technology, Inc.		
KMS		WO-02/45871-A1	06-13-2002	Angstrom Systems Inc.		
KMS		DE-198 51 824-A1	05-11-2000	Siemens AG		
KMS		WO-03/052807-A1	06-26-2003	Tokyo Electron Limited		
KMS		JP-9-82650-A	03-28-1997	Kokusai Electric Co. Ltd.		
KMS		JP-10-223719-A	08-21-1998	Dainippon Screen Mfg. Co. Ltd.		
KMS		JP-4-100533-A	04-02-1992	Mitsubishi Electric Corp.		
KMS		SU-598630	03-25-1978	Veremeichuk		
KMS		JP-2002-164336-A	06-07-2002	Sony Corporation		√
KMS		WO-02/073329-A2	09-19-2002	Applied Materials, Inc.		
KMS		WO-03/035927-A2	05-01-2003	Applied Materials, Inc.		
KMS		WO-01/46490-A1	06-28-2001	Lam Research Corporation		
KMS		WO-98/37258-A1	08-27-1998	Moore Epitaxial Inc.		
KMS		WO-02/081771-A2	10-17-2002	Angstrom Systems, Inc.		
KMS		WO-99/08610-A1	02-11-1999	Applied Komatsu Technology, Inc.		
Examiner Signature	/Kelly Stouffer/			Date Considered	08/21/2006	

Substitute for form 1449A/B/PTO  <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  (Use as many sheets as necessary)				<b>Complete if Known</b>	
				Application Number	10/665,908—Conf. #7052
				Filing Date	September 18, 2003
				First Named Inventor	Demetrius Sarigiannis
				Art Unit	1763
				Examiner Name	Rudy Zervigon
Sheet	11	of	13	Attorney Docket Number	108298722US

KMS		WO-02/48427-A1	06-20-2002	Tokyo Electron Limited		
KMS		EP-1 167 569-A1	01-02-2002	IPS Limited		
KMS		WO-00/40772-A1	07-13-2000	Genus, Inc.		
KMS		JP-11-172438-A	06-29-1999	Samsung Electron Co. Ltd.		✓
KMS		JP-8-34678-A	02-06-1996	Matsushita Electric Works Ltd.		✓
KMS		JP-6-151558-A	05-31-1994	Tokyo Electron Ltd.		✓
KMS		JP-6-342785-A	12-13-1994	Fujitsu Ltd.		✓
KMS		JP-2001-261375-A	09-26-2001	Toshiba Ceramics Co. Ltd.		✓
KMS		JP-2001-254181-A	09-18-2002	Tokyo Electron Ltd.		✓

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. \* CITE NO.: Those application(s) which are marked with an asterisk (\*) next to the Cite No. are not supplied (under 37 CFR 1.98(a)(2)(iii)) because that application was filed after June 30, 2003 or is available in the IFW. \* Applicant's unique citation designation number (optional). \* See Kinds Codes of USPTO Patent Documents at [www.uspto.gov](http://www.uspto.gov) or MPEP 901.04. \* Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). \* For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. \* Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST.16 if possible. \* Applicant is to place a check mark here if English language Translation is attached.

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
KMS		Integrated Process Systems Ltd., "ALD & CVD", 2 pages, retrieved from the Internet on December 11, 2001, < <a href="http://www.lps-tech.com/eng/pro-p2-2.htm">http://www.lps-tech.com/eng/pro-p2-2.htm</a> >.	
KMS		Deublin Company, "Rotating Unions", 1 page, retrieved from the Internet on February 4, 2002, < <a href="http://www.com/products/rotatingunions.htm">http://www.com/products/rotatingunions.htm</a> >.	
KMS		CAMERON, I., "Atomic Layer Deposition Chamber Works at Low Temperatures", 2 pages, Electronic Times, July 19, 2001, < <a href="http://www.electronicetimes.com/story/OEG20010719S0042">http://www.electronicetimes.com/story/OEG20010719S0042</a> >.	
KMS		Cutting Edge Optonics, 600W QCW Laser Diode Array, Part Number: ARR48P600, 2 pages, October 2001, < <a href="http://www.ceolaser.com">www.ceolaser.com</a> >.	
KMS		HENNING, A.K., et al., "Microfluidic MEMS for Semiconductor Processing," IEEE Trans. Components, Packaging, and Manufacturing Technology B21, pp. 329-337, 1998.	
KMS		FITCH, J.S., et al., "Pressure-Based Mass-Flow Control Using Thermopneumatically-Actuated Microvalves," Proceedings, Sensors and Actuators Workshop, pp. 162-165 (Transducers Research Foundation, Cleveland, OH, 1998).	
KMS		HENNING, A.K., "Liquid and gas-liquid phase behavior in thermopneumatically actuated microvalves," Proceedings, Micro Fluidic Devices and Systems (SPIE, Bellingham, WA, 1998; A.B. Frazier and C.H. Ahn, eds.), Vol. 3515, pp. 53-63.	

Examiner Signature	/Kelly Stouffer/	Date Considered	08/21/2006
--------------------	------------------	-----------------	------------

Substitute for form 1449A/B/PTO				<b>Complete if Known</b>	
<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  <i>(Use as many sheets as necessary)</i>				Application Number	10/665,908—Conf. #7052
				Filing Date	September 18, 2003
				First Named Inventor	Demetrius Sarigiannis
				Art Unit	1763
				Examiner Name	Rudy Zervigon
Sheet	12	of	13	Attorney Docket Number	108298722US

KMS		HENNING, A.K., et al., "Performance of MEMS-Based Gas Distribution and Control Systems for Semiconductor Processing", 8 pages, Proceedings, SEMICON West Workshop on Gas Distribution (SEMI, Mountain View, CA, 1998).	
KMS		MAILLEFER, D., et al., "A High-Performance Silicon Micropump for Disposable Drug Delivery Systems," pp. 413-417, IEEE, 2001.	
KMS		HENNING, A.K., et al., "A thermopneumatically actuated microvalve for liquid expansion and proportional control", Proceedings, TRANSDUCERS '97: 1997 International Solid State Sensors and Actuators Conference, pp. 825-828.	
KMS		University of California, Berkeley, University Extension, "Atomic Layer Deposition," 5 pages, September 24-25, 2001, < <a href="http://www.unex.berkeley.edu/eng/br225/1-1.html">http://www.unex.berkeley.edu/eng/br225/1-1.html</a> >.	
KMS		ENGELKE, F., et al., "Determination of Phenylthiohydantoin-Amino Acids by Two-Step Laser Resorption/Multiphoton Ionization," Analytical Chemistry, Vol. 59, No. 6, pp. 909-912, March 15, 1987, The American Chemical Society.	
KMS		COWIN, J.P., et al., "Measurement of Fast Desorption Kinetics of D2 From Tungsten By Laser Induced Thermal Desorption," Surface Science, Vol. 78, pp. 545-564, 1978, North-Holland Publishing Company.	
KMS		READY, J.F., "Effects Due to Absorption of Laser Radiation," Journal of Applied Physics, Vol. 36, No. 2, pp. 462-468, February 1965, Journal of Applied Physics, American Institute of Physics.	
KMS		ZARE, R.N., et al. "Mass Spectrometry of Molecular Adsorbates Using Laser Desorption/Laser Multiphoton Ionization," Bulletin of the Chemical Society of Japan, Vol. 61, No. 1, pp. 87-92, January 1988.	
KMS		Tokyo Electron Limited, Plasma Process System, Trias SPA, 1 page, retrieved from the Internet on October 16, 2004, < <a href="http://www.tel.com/eng/products/spe/sdtriasspa.htm">http://www.tel.com/eng/products/spe/sdtriasspa.htm</a> >.	
KMS		OLSSON, A., "Valve-less Diffuser Micropumps", ISSN 0281-2878, 66 pages, 1998.	
KMS		BARDELL, R.L., et al., "Designing High-Performance Micro-Pumps Based on No-Moving-Parts Valves", DSC-Vol. 62/HTD-Vol. 354, Microelectromechanical Systems (MEMS) ASME 1997, pp. 47-53.	
KMS		HENNING, A.K., et al., "Performance of MEMS-Based Gas Distribution and Control Systems for Semiconductor Processing," Proceedings, Micromachined Devices and Components (SPIE, Bellingham, WA, 1998; P.J. French and K. Chau, eds.), Vol. 3514, pp. 159-170.	
KMS		HENNING, A.K. et al., "Contamination Reduction Using MEMS-BASED, High-Precision Mass Flow Controllers," Proceedings, SEMICON West Symposium on Contamination Free Manufacturing for Semiconductor Processing (SEMI, Mountain View, CA, 1998), pp. 1-11.	
KMS		HENNING, A.K., "Microfluidic MEMS," Proceedings, IEEE Aerospace Conference, Paper 4.906 (IEEE Press, Piscataway, NJ, 1998), 16 pages.	

Examiner Signature	/Kelly Stouffer/	Date Considered	08/21/2006
--------------------	------------------	-----------------	------------

Substitute for form 1449A/B/PTO  <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  (Use as many sheets as necessary)		<b>Complete if Known</b>			
		Application Number	10/665,908—Conf. #7052		
		Filing Date	September 18, 2003		
		First Named Inventor	Demetrius Sarigiannis		
		Art Unit	1763		
		Examiner Name	Rudy Zervigon		
Sheet	13	of	13	Attorney Docket Number	108298722US

KMS		PETERS, L., "Thermal Processing's Tool of Choice: Single-Wafer RTP or Fast Ramp Batch?" Semiconductor International, April 1, 1998, 8 pages, < <a href="http://www.e-incite.net/semiconductor/index.asp?alyout+article&amp;articleid=CA163937">http://www.e-incite.net/semiconductor/index.asp?alyout+article&amp;articleid=CA163937</a> >.	
KMS		The University of Adelaide, Australia, Department of Chemistry, "Spectroscopy", 2 pages, retrieved from the Internet on February 9, 2002, < <a href="http://www.chemistry.adelaide.edu.au/external/Soc-Rel/Content/spectros.htm">http://www.chemistry.adelaide.edu.au/external/Soc-Rel/Content/spectros.htm</a> >.	
KMS		Deublin Company, "Sealing," 2 pages, retrieved from the Internet on February 4, 2002, < <a href="http://www.deublin.com/products/sealing.htm">http://www.deublin.com/products/sealing.htm</a> >.	
KMS		Deublin Company, "Precision Rotating Connections for Water, Steam, Air, Hydraulic, Vacuum, Coolant and Hot Oil Service," 1 page, retrieved from the Internet on February 4, 2002, < <a href="http://www.deublin.com">http://www.deublin.com</a> >.	
KMS		Integrated Process Systems Ltd., "Nano-ALD", 2 pages, retrieved from the Internet on December 11, 2001, < <a href="http://www.ips-tech.com/eng/pro-p2.htm">http://www.ips-tech.com/eng/pro-p2.htm</a> >.	
KMS		Integrated Process Systems Ltd., "Welcome to IPS Ltd.", 1 page, retrieved from the Internet on December 11, 2001, < <a href="http://www.ips-tech.com/eng/main.htm">http://www.ips-tech.com/eng/main.htm</a> >.	
KMS		TAKAHASHI, K et al., "Process Integration of 3D Chip Stack with Vertical Interconnection," pp. 601-609, 2004 Electronic Components and Technology Conference, IEEE, June 2004.	

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

<sup>1</sup>Applicant's unique citation designation number (optional). <sup>2</sup>Applicant is to place a check mark here if English language Translation is attached.

Examiner Signature	/Kelly Stouffer/	Date Considered	08/21/2006
--------------------	------------------	-----------------	------------